



PTO/SB/08B (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Institute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 1 of 1

Complete if Known

| | |
|------------------------|----------------------|
| Application Number | 10/613,700 |
| Filing Date | July 3, 2003 |
| First Named Inventor | Khursheed, Anjam |
| Art Unit | 2872 |
| Examiner Name | Not assigned yet |
| Attorney Docket Number | NAA 0016 PA/41049.18 |

NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| JB | | J. STOHR & S. SANDERS, "X-ray spectro-microscopy of complex materials and surfaces", IBM J. Res Develop, (2000), vol. 44, p. 535-551. | |
| JB | | Omicron Vakuumphysik GMBH, "Focus PEEM", January 2001, Germany | |
| JB | | D. PREIKSZAS et al., "SMART electron optics", 12th European Congress on Electron Microscopy, Proceedings Volume III, Instrumentation and Methodology, (2000), p. 18-84. | |
| JB | | H. SPIECKER et al., "Time-of-Flight Photoelectron Emission Microscopy TOF-PEEM: first results", Nucl. Instrum. and Methods in Phys. Res., (1998), A 406, p. 499-506. | |
| JB | | G.K.L. MARX et al., "Multipole WIEN-filter for a high-resolution X-PEEM", Journal of Electron Spectroscopy and Related Phenomena, (1997), Vol. 84, p. 251-61. | |
| JB | | A. KHURSHEED, "Ultimate resolution limits for scanning electron microscope immersion objective lenses," Optik, (2002), vol. 113, no. 2, p. 67-77. | |
| JB | | B.P. TONNER et al., "A Photoemission microscope with a hemispherical capacitor energy filter", Journal of Electron Spectroscopy & Related Phenomena, (1997), vol. 84, p. 211-29 | |
| JB | | J.E. Barth & P. Kruit, "Addition of different contributions to the charged particle probe size", Optik, (1996), vol. 101, no. 3, p. 101-109. | |
| | | | |
| | | | |

| | | | |
|--------------------|--------------------|-----------------|---------|
| Examiner Signature | <i>Jack Berman</i> | Date Considered | 6/28/04 |
|--------------------|--------------------|-----------------|---------|

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.